

IRRADIATION BEHAVIOR OF PYROLYTIC SILICON CARBIDE

R. J. Lauf

Ceramic Technology Group, Metals and Ceramics Division, Oak Ridge National Laboratory, P. O. Box X, Oak Ridge, Tennessee 37830

Fuel particles for the High-Temperature Gas-Cooled Reactor (HTGR) contain a layer of pyrolytic silicon carbide to act as a miniature pressure vessel and primary fission-product barrier. Optimization of the SiC with respect to fuel performance involves four areas of study. (a) Characterization of as-deposited SiC coatings,¹ (b) thermodynamics and kinetics of chemical reactions between SiC and fission products,² (c) irradiation behavior of SiC in the absence of fission products, and (d) combined effects of irradiation and fission products. This paper reports the behavior of SiC deposited on inert microspheres and irradiated to fast-neutron fluences typical of HTGR fuel at end-of-life.

EXPERIMENTAL

Silicon carbide was deposited on carbon microspheres in a fluidized bed by the decomposition of methyltrichlorosilane (CH_3SiCl_3) in an excess of hydrogen.³ The coated microspheres were irradiated to fast neutron fluences up to $8.8 \times 10^{25} \text{ n/m}^2$ ($E > 29 \text{ eV}$) in the High Flux Isotope Reactor at temperatures from 950 to 1350°C. After irradiation, the SiC layers were removed from the particles and prepared for TEM by standard techniques.⁴

CONF-830871--7

RESULTS

DE83 017142

As-deposited pyrolytic silicon carbide, Fig. 1, contains a high stacking fault density that generally increases with increasing coating rate.¹ Small cavities are sometimes present, frequently arranged in circumferential bands. These cavities are postulated to arise during fluctuations or local interruptions in the coating process.⁵

Irradiation at 1050°C and below produces small (~50Å) defect clusters (Fig. 2) which frequently lie along the remains of stacking faults. A defect-free region approximately 100Å wide exists along grain boundaries. Irradiation at higher temperatures (1150°C) produces voids (Fig. 3) that are typically 50Å in diameter. The voids lie parallel to remnant stacking faults in some grains but are distributed randomly in others. The foregoing observations are in substantial agreement with the work of Price⁶ who used pyrolytic SiC disks rather than actual coated particles.

The influence of process variables on irradiation behavior can be summarized as follows. (1) A relatively high initial stacking fault density tends to inhibit void formation, suggesting that stacking faults, like grain boundaries, form a sink for point defects. (2) Any cavities initially present in the SiC are not "healed" during irradiation, so a low-density coating remains inferior to a high-density coating.

¹R. J. Lauf and D. N. Braski, ORNL/TM-7571 (1981).

²R. L. Pearson, R. J. Lauf, and T. B. Lindemer, ORNL/TM-8059 (1982).

³J. I. Federer, ORNL/TM-5152 (1977).

⁴R. J. Lauf and H. Keating, 38th Ann. Proc. Electron Microscopy Soc. Amer., 196-7, G. W. Bailey, Editor, 1980.

⁵R. J. Lauf and D. N. Braski, ORNL/TM-7209 (1980).

⁶R. J. Price, J. Nucl. Mat. 48(1), 47-57 (1973).

Work supported by the U.S. Department of Energy under contract W-7405-eng-26 with the Union Carbide Corporation.

Fig. 1. Pyrolytic β -SiC, as deposited. Growth direction is upward. Note stacking faults and small cavities.

Fig. 2. Damage clusters in SiC irradiated at 1050°C to 7.3×10^{25} n/m².

Fig. 3. Voids in SiC irradiated at 1150°C to 7.6×10^{25} n/m².



Fig. 1. Pyrolytic β -SiC, as deposited. Growth direction is upward. Note stacking faults and small cavities.

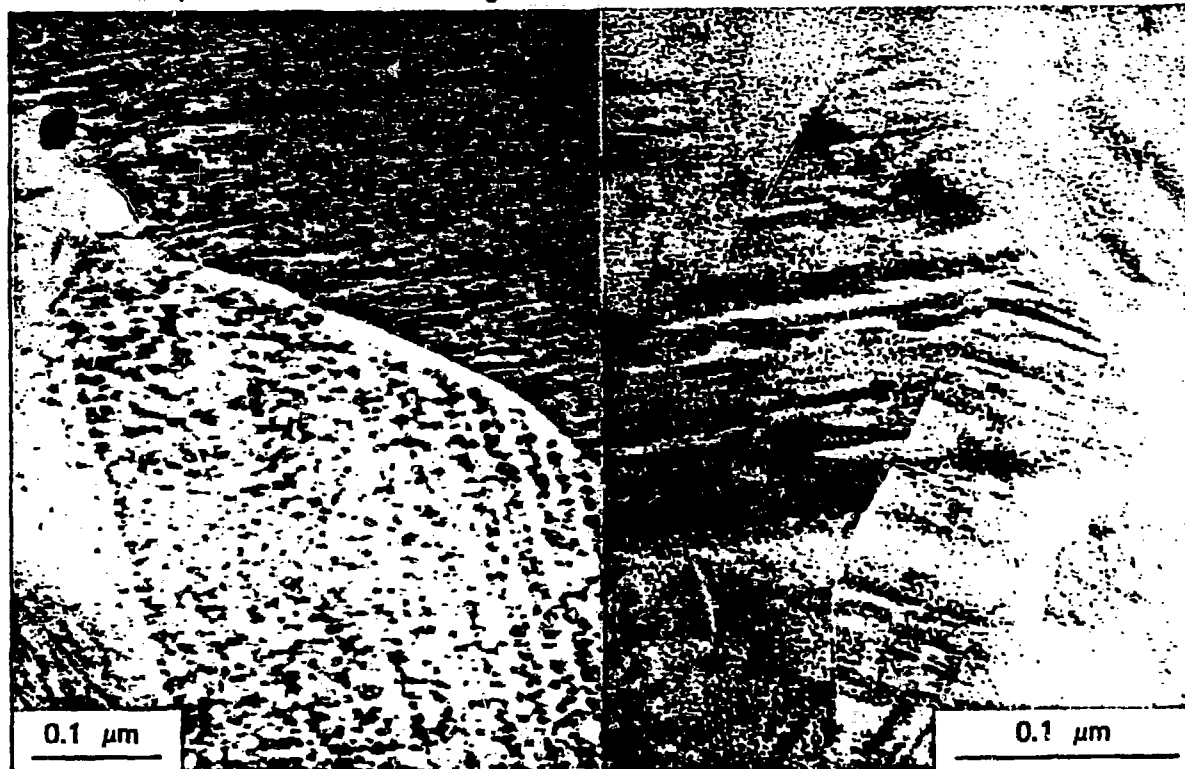


Fig. 2. Damage clusters in SiC irradiated at 1050°C to $7.3 \times 10^{25} \text{ n/m}^2$.

Fig. 3. Voids in SiC irradiated at 1150°C to $7.6 \times 10^{25} \text{ n/m}^2$.

DISCLAIMER

This report was prepared as an account of work sponsored by an agency of the United States Government. Neither the United States Government nor any agency thereof, nor any of their employees, makes any warranty, express or implied, or assumes any legal liability or responsibility for the accuracy, completeness, or usefulness of any information, apparatus, product, or process disclosed, or represents that its use would not infringe privately owned rights. Reference herein to any specific commercial product, process, or service by trade name, trademark, manufacturer, or otherwise does not necessarily constitute or imply its endorsement, recommendation, or favoring by the United States Government or any agency thereof. The views and opinions of authors expressed herein do not necessarily state or reflect those of the United States Government or any agency thereof.